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First demonstration of a 331-beam SEM

[C. Riedesel](#), [I. Müller](#) ([/profile/Ingo.Müller-4177247](#)), [N. Kaufmann](#) ([/profile/Nicolas.Kaufmann-4177248](#)), [A. Adolf](#) ([/profile/Andreas.Adolf-4177250](#)), [N. Kämmer](#) ([/profile/Nico.Kaemmer-4177253](#)), [H. Fritz](#) ([/profile/Hans.Fritz-4177254](#)), [A. L. Eberle](#) ([/profile/Anna-Lena.Keller-8652](#)), [D. Zeidler](#) ([/profile/Dirk.Zeidler-55942](#)).

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Abstract

We have demonstrated the successful operation of a multi-beam scanning electron microscope with 331 electron beams for the first time. This makes it the world's fastest SEM. The underlying architecture of the existing multi-beam mSEM technology fully supports the scale-up of the number of electron beams to 331. Scaling beyond this number is feasible.

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